

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: S. KADLEC, et al.

Serial No: 10/798,331

Filed: March 12, 2004

Title: METHOD FOR MANUFACTURING SPUTTER-COATED
SUBSTRATES, MAGNETRON SOURCE AND SPUTTERING
CHAMBER WITH SUCH SOURCE

Group: 1795

Examiner: Michael A. Band
Conf. No.: 6134Enter BCE
11/04/09
AS**AMENDMENT AFTER FINAL REJECTION****BOX - AF**Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

October 16, 2009

Sir:

In response to the Office Action dated July 1, 2009, please amend the above-identified application as listed below and as set forth on the following pages:

Amendments to the Specification

Amendments to the Claims

Remarks are included following the amendments.

An Appendix with a copy of Fig. 9 of the application drawings to which colors have added, is attached following the Remarks. The colored drawing is referred to in the Remarks.

